

THICKNESS MAPPING SYSTEM FOR SEMICONDUCTOR & PCB

ST 2080

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Thickness Mapping Measurement (ST2080)

Wavelength Range	420nm ~ 640nm
Thickness Range	350Å ~ 3µm (Depends on Samples)
Minimum Spot Size	1.35µm(5X), 0.135µm(50X)
Target Area	864 x 648µm / 86.4 x 64.8µm
Lens	5X, 50X

Measurement Result

Size of sample stage: 200mm x 200mm

Thickness Range

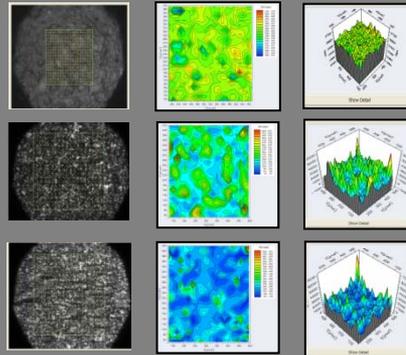
CCD

2D

3D

Thick ↑

↓ Thin

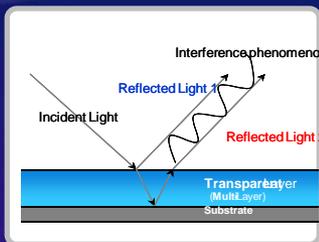


Measuring Thousands of Points at Once

Sub-Micron Spot Size(0.135µm)

2D & 3D Mapping

High Efficiency Monitoring for Uniformity



$$R_{\lambda} = f(n_{\lambda}, k_{\lambda}, t_{\lambda})$$

n: Refractive Index
k: Extinction Coefficient
t : Thickness